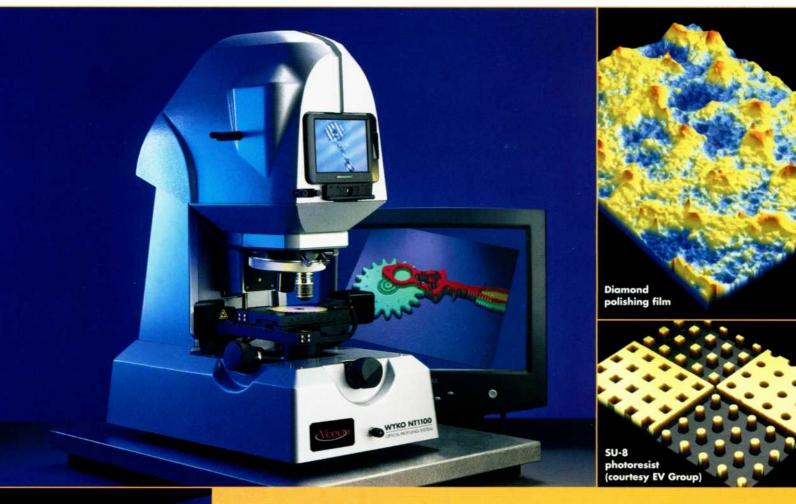
Wyko NT1100 Optical Profiling System

Quantitative 3D Topography for Research and Low-Volume Production





The Wyko® NT1100 provides accurate, non-contact surface metrology for applications in MEMS, thick films, optics, ceramics, advanced materials and many more.

- Accurate surface topography in a small footprint
- Sub-nanometer vertical resolution at all magnifications
- Motorized stage for stitching large area measurements
- Complete system including Wyko Vision®32 analysis software







Fast and repeatable, the NT1100 utilizes white light interferometry for high resolution 3D surface measurements, from sub-nanometer roughness to millimeter-high steps. On super-smooth or rough surfaces, the versatile NT1100 provides repeatable surface measurement for R&D, wear and failure analysis, and process control.

The cost-effective NT1100 offers all the advantages of industry-standard Wyko optical profiling, including the full Wyko Vision®32 analytical software package. Vision32, the industry's most comprehensive analysis program, provides over 200 tools to quantify and visualize surface data — all standard.

The NT1100 has the performance features of larger NT Series instruments: easy measurement setup, fast acquisition, comprehensive analysis and Angstrom-level repeatability. The Data Stitching option adds a motorized stage and support software to rapidly scan large surface areas.



Call 520.741.1044 or 1.888.24.VEECO

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Specifications

SYSTEM

Measurement Techniques

Measurement Capability

Objectives

Field-of-View Lenses Measurement Array Light Source

Stages

Optical Assembly

Video Display Computer System

Software

PERFORMANCE

Vertical Measurement Range Vertical Resolution¹ RMS Repeatability² Vertical Scan Speed Lateral Spatial Sampling

Reflectivity

Field-of-View

ENVIRONMENT

Temperature Range Humidity Range Vibration

DIMENSIONS

Microscope

WEIGHT

Microscope Shipping Weight

POWER REQUIREMENTS

Input Voltage

Power Consumption
Compressed Air

optical phase-shifting and white light vertical scanning interferometry

three-dimensional, non-contact, surface profile measurements

1.5X, 2.5X, 5.0X, 10X, 20X, 50X; long working distance objectives available;

optional manual turret

0.5X, 0.75X, 1.0X, 1.5X, 2.0X

user-selectable, maximum array 736 x 480

tungsten halogen lamp (user-replaceable); manual filter selection

manual; \pm 50.8mm (\pm 2 in.) X/Y translation, \pm 4° tip/tilt; optional automated stitching

stage, ± 50.8 mm (2 in.) X/Y integrated illuminator; interchangeable

discrete field-of-view lenses; closed-loop precision vertical scanning assembly

127mm (5 in.) monochrome monitor

PC with latest Celeron® processor, 430mm (17 in.) SVGA monitor; optional printers and network cards

114 1 10 : 800 f

Wyko Vision®32 software running under Microsoft® Windows XP®

0.1nm to 1mm < 1Å Ra

0.01 nm

up to 7.2 µm/sec (288 µin./sec)

0.08 to 13.1 µm

8.24mm to 0.05mm (larger areas with

Data Stitching option)

1% to 100%

between 15 and 30 °C (59 to 86 °F)

≤ 80%, non-condensing

optional isolation system (recommended)

399mm W x 508mm D x 737mm H (15.5in, W x 20in, D x 29in, H)

does not exceed 56.7 kg (125 lbs) 204.1 kg (450 lbs)

user-selectable 100-120 VAC / 200-240 VAC , 50-60 Hz

<300W

4.2 – 7.0 kg/cm (60–100 PSI) for optional isolation system

¹As demonstrated by a PSI measurement with nulled fringes on a SiC reference mirror.

²As demonstrated by taking the one sigma Rq value of 30 PSI repeatability measurements on a SiC reference mirror.